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Substitute for form 1449B/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 3

Complete if Known

Application Number	09/932,239
Filing Date	17 August 2001
First Named Inventor	Christophe Pierrat
Group Art Unit	1756
Examiner Name	Mohamedulla, S.
Attorney Docket Number	NMTI 1002-3

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

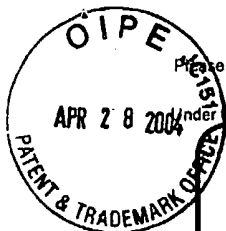
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SPM	C1	SAKATA, MIWA, et al., "A Novel Radiation Sensitive Spin-on-glass Convertible into SiO ₂ and the Simple Fabrication Process Using It," 26 July 1993* (*ATI Bell Labs fax date), 3 pages.	
SPM	C2	PISTOR, THOMAS V., "Rigorous 3D Simulation of Phase Defects in Alternating Phase-Shifting Masks," Proceedings of SPIE 4562-1038 (March 2002), 13 pages	
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SPM		SEWELL, HARRY, et al., "An Evaluation of the Dual Exposure Technique," (As early as 2002*), 11 pages *The date is based on references 8&9 of the article of 16 Feb 2001 and 27 Feb 2002, respectively.	
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SPM		SEMMIER, ARMIN, et al., "Application of 3D EMF Simulation for Development and Optimization of Alternating Phase Shifting Masks," Proc. of SPIE 4346-37, 1 March 2001, 12 pages.	
SPM		WONG, ALFRED K., "Polarization Effects in Mask Transmission," Proc. of SPIE 1674, 8 March 1992, 8 pages.	
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Examiner Signature	Mohamedulla	Date Considered	6/21/04
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SPM		SUGAWARA, MINORU, et al., "Defect printability study of attenuated phase-shifting masks for specifying inspection sensitivity," Proc. SPIE 2621-49, September 1995, 16 pages.	
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SPM		LEVENSON, MARC D., et al., "Phase Phirst! An improved strong-PSM paradigm," Proc. SPIE 4186-42, September 2000, 10 pages.	
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SPM		RONSE, KURT, et al., "Comparison of various phase shift strategies and application to 0.35 um ASIC designs," Proc. SPIE 1927, 1993, 15 pages.	
SPM		ROSENBLUTH, ALAN E., et al., "Optimum Mask and Source Patterns to Print a Given Shape," Proc. SPIE 4346-49, 1 March 2001, 17 pages.	

Examiner Signature	Mohamedulla	Date Considered	6/21/04
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SPM		COTE, MICHEL, et al., "A Practical Application of Full-Feature Alternating Phase-Shifting Technology for a Phase-Aware Standard-Cell Design Flow," 1 June 2001, 6 pages.	
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SPM		MCCALLUM, MARTIN, et al., "Alternating PSM Mask Performance - A Study of Multiple Fabrication Technique Results," Proc. SPIE 4346-723, September 2001, 6 pages.	

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